



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Gaillard, et al.

Serial No.: 10/789,209

Confirmation No.: 9101

Filed: February 27, 2004

For: Method of Decreasing the
K Value in SIOC Layer
Deposited by Chemical
Vapor Deposition

Group Art Unit: 2818

Examiner: David Nhu

Free
Okay

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING	
37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>3/8</u> , 2005 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.	
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Date	Signature

Dear Sir:

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The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

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